# Eda Goldenberg

## List of Publications by Citations



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|---|---|---|---|
| 30 papers | 607 citations | 16 h-index | 24 g-index |
| 30 ext. papers | 640 ext. citations | 3 avg, IF | 3.75 L-index |

| # | Paper | IF | Citations |
|---|---|---|---|
| 30 | Hollow cathode plasma-assisted atomic layer deposition of crystalline AlN, GaN and AlxGa1−xN thin films at low temperatures. *Journal of Materials Chemistry C*, **2014**, 2, 2123-2136 | 7.1 | 113 |
| 29 | Effects of deposition time and temperature on the optical properties of air-annealed chemical bath deposited CdS films. *Thin Solid Films*, **2006**, 515, 1688-1693 | 2.2 | 50 |
| 28 | Modeling the optical properties of tin oxide thin films. *Thin Solid Films*, **2009**, 517, 5146-5150 | 2.2 | 43 |
| 27 | Chemical and thermal stability of the characteristics of filtered vacuum arc deposited ZnO, SnO2and zinc stannate thin films. *Journal Physics D: Applied Physics*, **2007**, 40, 5220-5226 | 3 | 38 |
| 26 | The effect of annealing on filtered vacuum arc deposited ZnO thin films. *Surface and Coatings Technology*, **2007**, 201, 7266-7272 | 4.4 | 30 |
| 25 | Properties of SnO2 films fabricated using a rectangular filtered vacuum arc plasma source. *Thin Solid Films*, **2008**, 516, 5079-5086 | 2.2 | 30 |
| 24 | Low-Temperature Deposition of Hexagonal Boron Nitride via Sequential Injection of Triethylboron and N2/H2 Plasma. *Journal of the American Ceramic Society*, **2014**, 97, 4052-4059 | 3.8 | 28 |
| 23 | Influence of annealing on the physical properties of filtered vacuum arc deposited tin oxide thin films. *Journal of Non-Crystalline Solids*, **2007**, 353, 2595-2602 | 3.9 | 28 |
| 22 | Air annealing effects on the optical properties of ZnO–SnO2thin films deposited by a filtered vacuum arc deposition system. *Semiconductor Science and Technology*, **2006**, 21, 364-369 | 1.8 | 25 |
| 21 | Fabrication of flexible polymer–GaN core–shell nanofibers by the combination of electrospinning and hollow cathode plasma-assisted atomic layer deposition. *Journal of Materials Chemistry C*, **2015**, 3, 5199-5206 | 7.1 | 22 |
| 20 | Filtered vacuum arc deposition of transparent conducting Al-doped ZnO films. *Thin Solid Films*, **2006**, 515, 885-890 | 2.2 | 22 |
| 19 | Characteristics of filtered vacuum arc deposited ZnO–SnO2 thin films on room temperature substrates. *Optics Communications*, **2007**, 280, 114-119 | 2 | 20 |
| 18 | Effect of deposition conditions on the characteristics of ZnO–SnO2 thin films deposited by filtered vacuum arc. *Thin Solid Films*, **2006**, 515, 880-884 | 2.2 | 19 |
| 17 | Low-temperature grown wurtzite InxGa1−xN thin films via hollow cathode plasma-assisted atomic layer deposition. *Journal of Materials Chemistry C*, **2015**, 3, 9620-9630 | 7.1 | 16 |
| 16 | The effect of substrate temperature on filtered vacuum arc deposited zinc oxide and tin oxide thin films. *Journal of Crystal Growth*, **2007**, 299, 259-267 | 1.6 | 16 |
| 15 | Optical characterization of filtered vacuum arc deposited zinc oxide thin films. *Semiconductor Science and Technology*, **2006**, 21, 1303-1310 | 1.8 | 16 |
| 14 | Optical properties of transparent ZnO–SnO2thin films deposited by filtered vacuum arc. *Journal Physics D: Applied Physics*, **2006**, 39, 1878-1884 | 3 | 16 |

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|---|---|---|---|
| 13 | Structural, optical and electrical characteristics BaSrTiOx thin films: Effect of deposition pressure and annealing. *Journal of Non-Crystalline Solids*, **2017**, 475, 76-84 | 3.9 | 15 |
| 12 | Effect of O2/Ar flow ratio and post-deposition annealing on the structural, optical and electrical characteristics of SrTiO3 thin films deposited by RF sputtering at room temperature. *Thin Solid Films*, **2015**, 590, 193-199 | 2.2 | 13 |
| 11 | Low-temperature hollow cathode plasma-assisted atomic layer deposition of crystalline III-nitride thin films and nanostructures. *Physica Status Solidi C: Current Topics in Solid State Physics*, **2015**, 12, 394-398 | | 11 |
| 10 | Postdeposition annealing on RF-sputtered SrTiO3 thin films. *Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films*, **2017**, 35, 021505 | 2.9 | 9 |
| 9 | Optical characteristics of nanocrystalline AlxGa1□N thin films deposited by hollow cathode plasma-assisted atomic layer deposition. *Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films*, **2014**, 32, 031508 | 2.9 | 9 |
| 8 | Structural and optical characteristics of filtered vacuum arc deposited N:TiOx thin films. *Thin Solid Films*, **2013**, 537, 28-35 | 2.2 | 5 |
| 7 | The dependence of filtered vacuum arc deposited ZnO□nO2thin films characteristics on substrate temperature. *Journal Physics D: Applied Physics*, **2006**, 39, 5245-5251 | 3 | 5 |
| 6 | The effect of post-deposition annealing on the optical properties of filtered vacuum arc deposited ZnO□nO2. *Journal of Physics Condensed Matter*, **2007**, 19, 256206 | 1.8 | 4 |
| 5 | Hollow-cathode plasma-assisted atomic layer deposition: A novel route for low-temperature synthesis of crystalline III-nitride thin films and nanostructures **2015**, | | 2 |
| 4 | Zno nanostructures via hydrothermal synthesis on atomic layer deposited seed-layers **2015**, | | 1 |
| 3 | Phase determination of filtered vacuum arc deposited TiO2 thin films by optical modeling. *Thin Solid Films*, **2009**, 518, 1060-1066 | 2.2 | 1 |
| 2 | WS2 thin film based quartz crystal microbalance gas sensor for dimethyl methylphosphonate detection at room temperature. *Thin Solid Films*, **2022**, 745, 139097 | 2.2 | 0 |
| 1 | Electro-optical performances of nanostructured SrTiOx films: The effect of plasma power, Ar/O2 ratio and annealing. *International Journal of Applied Ceramic Technology*, **2021**, 18, 631-642 | 2 | |